

NCCAVS
CMP USER GROUP
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Topic: Advances in CMP Consumables, Materials and Tools

Meeting Date: April 16, 2020

Time: 1:00 pm – 4:00 pm

LOCATION: DUE TO THE COVID-19 OUTBREAK THIS MEETING HAS BEEN CHANGED FROM ONSITE LOCATION TO BEING A WEB-BASED MEETING!

**Co-Chairs: Michael Pevny, 3M Company, mpevny@mmm.com
Gene Davis, Texas Instruments, g-davis2@ti.com**

The Chemical Mechanical Planarization Users Group (CMPUG) Symposium on Advances in CMP Consumables, Materials and Tools commences on **April 16, 2020**. The symposium will provide an international forum for academic researchers, industrial practitioners and engineers from around the world for the exchange of information on state-of-the-art research in CMP semiconductor technology. The CMPUG promotes the exchange of opportunities, ideas, friendly relationships and research collaboration. The areas of focus for this meeting will be the following:

- CMP consumables and materials
- CMP Polishing and Metrology Tools
- CMP Process Integration

SPEAKERS/AGENDA

1:00 p.m. – Welcome and Acknowledgment of Sponsors: **Co-Chairs Michael Pevny, 3M)and Gene Davis, Texas Instruments**

1:10 p.m. – 100mm - Membrane Carrier Tuning for State of the Art CMP Process Development in R&D Environments, **Knut Gottfried, Fraunhofer ENAS**

1:35 p.m. – Holistic Approach to the Understanding CMP-Induced Defects, **Hong Jin Kim, Global Foundries**

2:00 p.m. – CMP – A Leap Forward; Capstone, **Catherine Bullock, Axus Technology**

2:25 p.m. – No Process Can Change Alone: An Integrated Approach to CMP Consumable Development and Manufacturing, **Stephen Bottiglieri, Saint Gobain Abrasives**

2:50 p.m. – Characterization of Large Particle Contaminants in CMP Slurries using Holographic Video Microscopy, **Laura Philips, Spheryx, Inc.**

3:25 p.m. - Case Studies Involving the Use of a 300-mm Brush Scrubber and Tribometer to: (A) Evaluate the Role of Anionic Supramolecular Assemblies in Post-STI-CMP Cleaning, and (B) Determine the Effect of Brush Nodule Placement Density on Shear Force in Time and Frequency Domains in Post-W-CMP Cleaning, **Ara Philipossian, Araca Inc.**

All approved presentations will be posted on the CMPUG Proceedings webpage within 2 weeks following the meeting.

- **If you would like to sponsor this meeting or list a banner ad on the User Group website, please check out our “NCCAVS Marketing/Sponsorship” opportunities at:**
<https://nccavs-usergroups.avsgroups.org/wp-content/uploads/2017/08/UG-Sponsor.pdf>